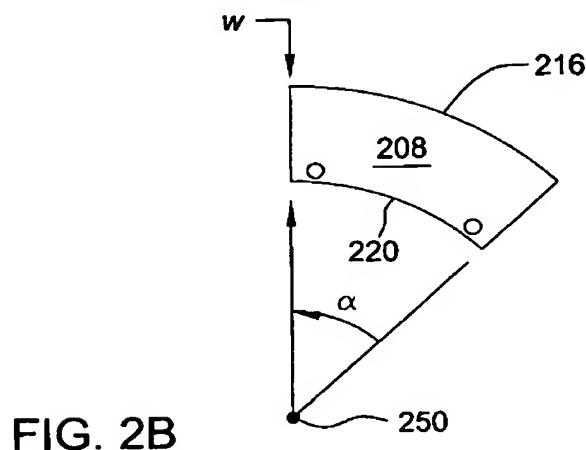
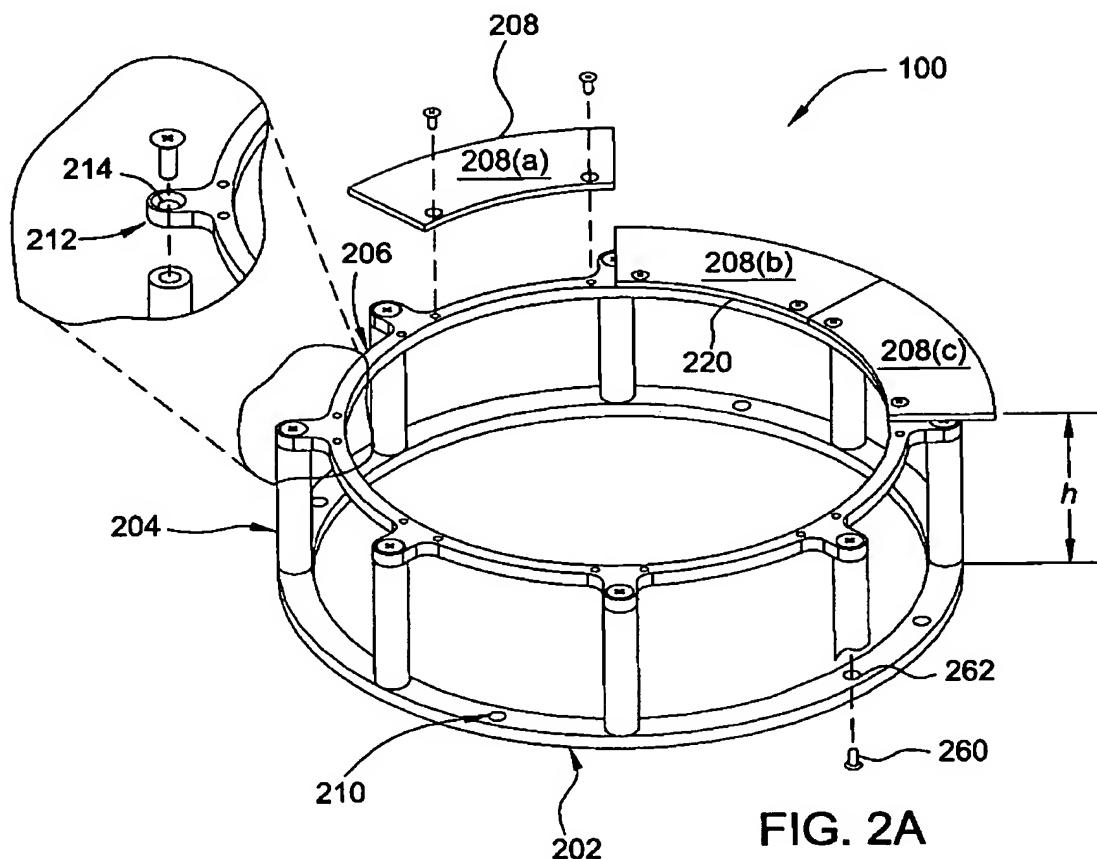


Replacement Sheet 1 of 2
Applicant: Bern, et al.
Title: APPARATUS FOR CONTROLLING
GAS FLOW IN A SEMICONDUCTOR
SUBSTRATE PROCESSING CHAMBER
Serial No. 10/821,310

2/5



Replacement Sheet 2 of 2
Applicant: Bera, et al.
Title: APPARATUS FOR CONTROLLING
GAS FLOW IN A SEMICONDUCTOR
SUBSTRATE PROCESSING CHAMBER
Serial No. 10/821,310

3/5

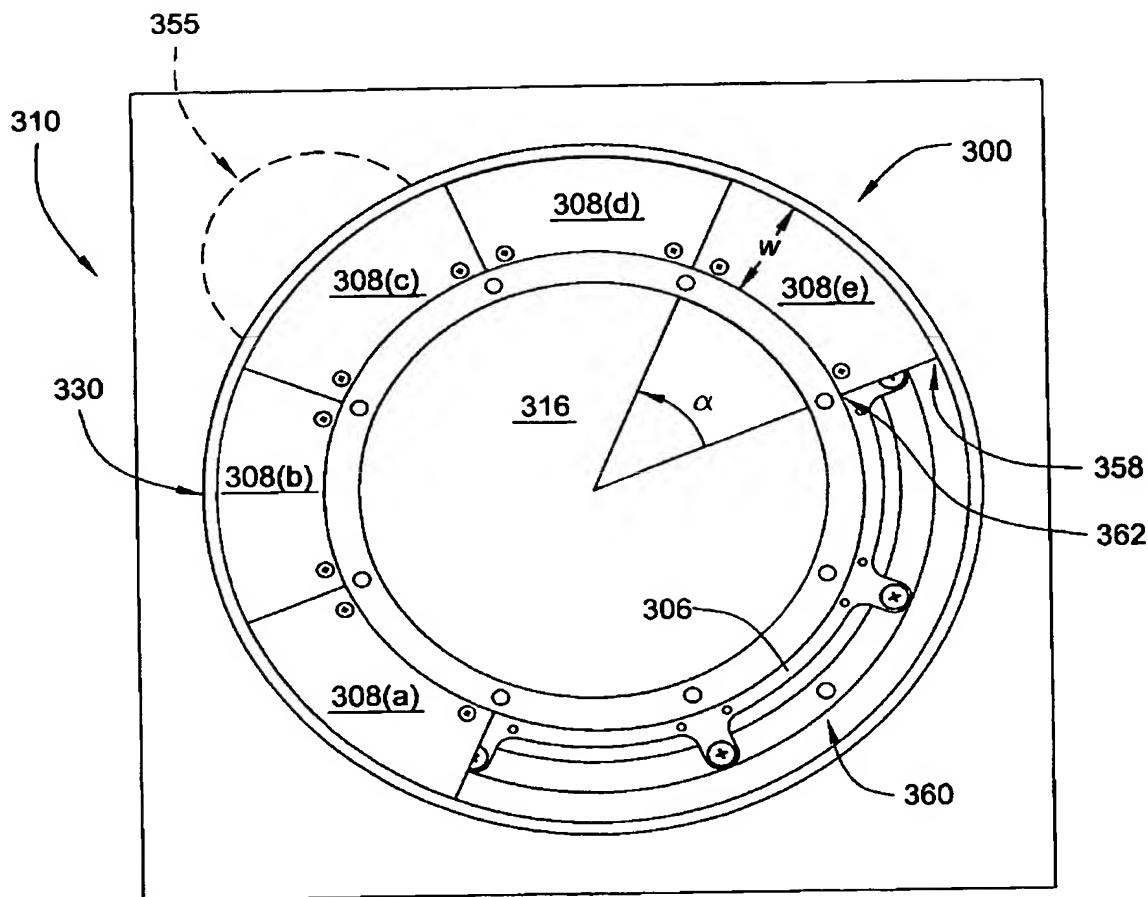


FIG. 3